

# Progress and Opportunities of the Transient Liquid Assisted Growth (TLAG) method

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### AIM: Design a robust, high throughput and flexible growth method for the manufacturing of CC at competitive cost/performance ratio



### **Opportunities of TLAG**

-High growth rates > 1000 nm/s

-Compatible with low-cost chemical solution deposition (CSD) and others (i.e Low Temperature PLD deposition, LTPLD)

- -Wide processing window
- -Compatible with different Rare Earch (RE) and nanocomposite growth
- -Well-suited for large area fabrication
- -Easily scalable manufacturing equipment

### Need of R&D in advanced CC materials

-Generate new ideas and understanding

-Develop breakthroughs that enable high-volume CC production at lower cost/performance

-Fast screening methodologies and AI approaches to guide predictions

-Contribute to making CC production a sustainable and transformative technology

### Outline

-Progess in process understanding and processing windows

-Growth rates

-High Throughput Experimentation approach

- -Vortex pinning and overdoping
- -Towards large area Coated Conductors



# Inks, pyrolysis and multidepositions in TLAG-CSD





Multifunctional ink Patent EP22382741

Adapted to multideposition with no loss in homogeneity





Also demonstrates for REBCO inks with RE= Y, Er, Gd, Sm, Yb



500 nm

MICMA

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B

# Understanding TLAG growth mechanisms through in-situ 2D X-Ray Diffraction (XRD)





## **TLAG kinetic phase diagram from evolution of phases**



### Wide processing window further controlled by RE ion

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Collab. Z. Wu, T. Kiss

(Gd/Y)BCO

10

6

8

9

4

ε

2

1

0

0

x (mm) 5

### 4 **High Throughput Experimentation using Combinatorial RE Compositional gradients** (Er<sub>x</sub>Y<sub>1-x</sub>)BCO

7

rich

100% Y

Y/RE

- 0,8000

- 0,6000

- 0,4000

- 0,2000

ູ່ອຸ**100% Er** 

1,11 -

2,13 1,62

2,64



(Er/Y)BCO

**Reference YBCO** 

m

λ (ww)

**Towards Machine Learning** 

strategies for J<sub>c</sub> prediction

N

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0

Scanning Hall Probe Microscopy

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12

m

9





(Patent EP22382741)

ESAS and CSSJ SUPERCONDUCTIVITY NEWS FORUM (global edition), Issue No. 59, May 2025. Presentation given at CCA 2025, March 11-13, 2025, Geneva, Switzerland.

## **Ortex Physics in TLAG Nancomposites**



# **Vortex Pinning anisotropy in TLAG films**







Nanocomposites decrease vortex dissipation and induce less anisotropy

, Vortex behaviour depends on T, H,  $\theta$  and process parameters

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F. Valles et al, Comm Mat 3 (2022)

# TLAG Vortex Pinning diagrams $J_c(T) = J_c^{iso-wk}(T) + J_c^{iso-str}(T) + J_c^{aniso-str}(T)$



### The overdoped state: Opportunity to increase pinning efficiency



# <sup>6</sup> Towards wide area TLAG Coated Conductors • ELECTRIC







**Colloidal Ink** scaled ~ liter

Slot die now with 40 mm-width printhead capabilities





Microstructure is reproduced in 250-750 nm CC High superconducting properties:  $J_c(77K) = 1.7-2 \text{ MA/cm}^2$ 

Construction of a furnace for 40 mm-wide tape is on going

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# **Conclusions and outlook**

- TLAG is a high-throughput process, very versatile and with a large processing window that can support large volume CC fabrication while reducing cost/performance ratio
- In-situ Synchrotron techniques are ideal to underpin the TLAG mechanisms
- High Throughput Experimentation with combinatorial gradients and AI should accelerate the selection of compositions and conditions
- Vortex pinning in the overdoped state is the future to achieve higher efficiency due to the increase in condensation energy in a robust way
- TLAG should be a large area processing method that adapts to the needs of increased production as well as opens to new applications







Magnetic Field